

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Eric NEYRET et al.

Application No.:

Group Art Unit:

Filed: September 25, 2003

Examiner:

For: METHOD FOR MINIMIZING SLIP LINE FAULTS
ON A SEMICONDUCTOR WAFER SURFACE

Attorney Docket No.: 4717-7800

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

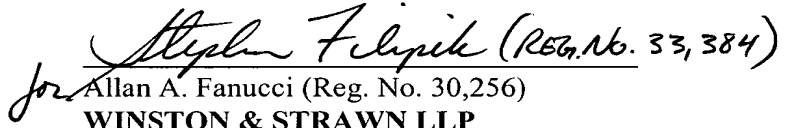
Pursuant to applicants' duty of disclosure under 37 C.F.R. 1.56, enclosed are copies of (5) references for the Examiner's review and consideration. These references are listed on the enclosed Form PTO-1449. A copy of a Preliminary Search Report in the counterpart French application is also enclosed.

It is respectfully requested that these references be made of record in this application by the Examiner's completion and return of Form PTO-1449.

No fee or certification is believed to be due for this submission since the references are being submitted concurrent with the filing of this application. Should any fees be required, however, please charge such fees to **Winston & Strawn LLP** Deposit Account No. 501-814.

Respectfully submitted,

Date: SEPTEMBER 25, 2003


Allan A. Fanucci (Reg. No. 30,256)
WINSTON & STRAWN LLP
CUSTOMER NO. 28765

Enclosures

(212) 294-3311

LIST OF REFERENCES CITED BY APPLICANT Form PTO-1449 <i>(Use several sheets if necessary)</i>					ATTY. DOCKET NO.:		APPLICATION NO.:	
					4717-7800			
					APPLICANT:			
					Eric NEYRET et al.			
					FILING DATE:		GROUP:	
					September 25, 2003			
U.S. PATENT DOCUMENTS								
*EXAMINE R INITIAL	CITE NO.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
	AA	5,359,693	10/1994	Nenyei et al.	392	418		
FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	AB	EP 1 041 612 A1	4/2000	Europe			X	
	AC	EP 1 193 749 A2	4/2002	Europe			X	
	AD	FR 2 797 713	2/2001	France				X
	AE	07321120 w/ English Abstract	12/1995	Japan			X	
OTHER REFERENCES <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>								
EXAMINER				DATE CONSIDERED				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								